

OBJECTIVES

- Get a basic knowledge of the cleanroom environment and the technical facilities required for its operation
- Identify and implement the main processes for microdevice fabrication
- Be able to use process equipments
- Provide a global vision of technological processes for an effective appropriation of the professional environment

TARGETED AUDIENCE & PREREQUISITES

Technicians, engineers and sales representatives in contact with cleanroom end-users through their professional activities. No prerequisites

PROGRAM



General introduction to the cleanroom environment

- Specificities of cleanroom environment
- Different classes of cleanrooms
- Gowning procedure, personal protective equipment and safety
- Technical facilities required to maintain the cleanroom environment (with a visit) : air treatment, water treatment, management of liquid and gaseous effluents



Microfabrication technologies in cleanrooms

- Definitions and theory
- Practical work inside the cleanrooms, implementation of the following microfabrication processes :
 - Thin film deposition by sputtering
 - Photolithography (single-side and alignment)
 - Reactive Ion Etching (RIE)
 - Thickness measurement by profilometry
 - Dicing

CUSTOMER BENEFITS



More than 30 years of experience and innovation for academic and industrial MEMS field



High ratio of practice (~70%) vs. theory



Up-to-date ISO 5 and ISO 7 cleanrooms on 650 sq-meter, opened in 2017



Located on a dynamic campus with high-tech platforms, quick and easy access from Paris center



Coffee-breaks and lunches in a private lounge included

Short ongoing training session

INITIATION TO CLEANROOM MICROFABRICATION TECHNOLOGIES

DURATION

2 days (14 h)

LOCATION

Noisy-le-Grand (93)
FRANCE

PUBLIC RATE

2 125 €

CONTACT

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